

FORM PTO-1449 (SUBSTITUTE)

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Applicant

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Group Art Unit

2125

INFORMATION DISCLOSURE
STATEMENT BY APPLICANT
(37 CFR 1.98(b))

U.S. PATENT DOCUMENTS

EXAMINER INITIALS		PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
	A						
	B						
	C						
	D						
	E						
	F						
	G						
	H						
	I						

FOREIGN PATENT DOCUMENT

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES NO
	J						
	K						
	L						
	M						
	N						

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

	O	1997 Proceedings Second International Chemical-Mechanical Polish (C.M.P.) for ULSI Multilevel Interconnection Conference (CMP-MIC). "A Mechanical Model for Dram Dielectric Chemical-Mechanical Polishing Process." Catalog No. 97ISMIC-200P, Library of Congress No. 89-644090, February 13-14, 1997, Santa Clara, CA, pp. 259-265.
	P	

EXAMINER

DATE CONSIDERED

8/29/05

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.